

2 A method of forming a planar waveguide structure, comprising forming a first graded
3 layer on a substrate, wherein the first graded layer comprises a first and a second optical
4 material, wherein the concentration of the first optical material increases with the height of the
5 first graded layer; forming a second graded layer on the first graded layer, the second graded
6 layer comprising the first and second optical materials wherein the concentration of the first
7 optical material decreases with the height of the second graded layer. The method further
8 including forming a uniform layer on the first graded layer, the uniform layer containing first
9 and second optical materials wherein the first optical material concentration is constant.

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